Special Issue

RF Devices: Technology and Progress

Message from the Guest Editor

RF MEMS is a type of MEMS device that processes radio frequency signals. RF MEMS can utilize MEMS technology to manufacture on-chip transmission lines, RF cavities, three-dimensional inductors, couplers, varactors, switches, filters, phase shifters and antennas. Compared with traditional RF devices, RF MEMS devices have many advantages, including their small size, insensitivity to acceleration, low DC power consumption, and ability to be fabricated on low-cost silicon or glass substrates. In addition, RF MEMS devices can be integrated with traditional silicon-based and gallium arsenide-based circuits, enabling miniaturization of RF processing systems. These advantages have led to significant applications in fields such as mobile communications, satellites, radars, etc. Accordingly, this Special Issue seeks to showcase research papers, short communications, and review articles that focus on novel technology and progress in RF MEMS and its use for various RF systems.

Guest Editor

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